

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DCKT. NO. M122-1913		Priority SERIAL NO. 09653.156	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Vishnu K. Agarwal		Priority FILING DATE August 31, 2000	
				Priority GROUP 2813			
U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
yft	AA	6,180,481	01/2001	Deboer et al			
	AB	6,218,256	04/2001	Agarwal			
	AC	6,104,049	08/2000	Solayappan et al			
	AD	6,180,447	01/2001	Park et al			
	AE	6,274,428	08/2001	Wu			
	AF	6,124,158	09/2000	Dautartas et al			
	AG	6,144,060	11/2000	Park et al			
	AH	5,316,982	05/1994	Taniguchi			
	AI	6,281,142	06/1999 05/2001	Basceri et al			
	AJ	6,204,172	09/1996 03/2001	Marsh			
	AK	5,432,732	07/1995	Ohmi			
	AL	6,242,299	06/2001	Hickert			
	AM	6,249,056	06/2001	Kwon			
	AN	6,291,289	09/2001	Rhodes			
	AO	6,174,770	01/2001	Chi			
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	AP						
	AQ						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
yft	AR		A.W. Ott, et al., "Atomic Layer Controlled Deposition of Al ₂ O ₃ Films Using Binary Reaction Sequence Chemistry", Applied Surface Science (107), 1996, pps. 128-136.				
	AS						
EXAMINER				DATE CONSIDERED			
yft				7/19/02			
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							

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